

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto                      Art Unit : 1792  
Serial No. : 10/689,617                      Examiner : Mahmoud Dahimene  
Filed : October 22, 2003                      Conf. No. : 4799  
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD  
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE

## MAIL STOP AF

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

## NOTICE OF APPEAL

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the action dated April 22, 2008, twice rejecting claims 1-95.

The fee in the amount of \$510 for the appeal fee is being paid concurrently herewith on the Electronic Filing System (EFS) by way of Deposit Account authorization. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: July 22, 2008

/Diana DiBerardino/

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